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Docket No.: P8375.0002
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Hidemitsu Aoki et al.

Application No.: 10/680,216

Confirmation No.: 7422

Filed: October 8, 2003

Art Unit: 1746

For: METHOD OF MANUFACTURING
SEMICONDUCTOR DEVICE AND
APPARATUS FOR CLEANING
SUBSTRATE

Examiner: Not Yet Assigned

RESPONSE TO RESTRICTION REQUIREMENT

MS Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the restriction requirement set forth in the Office Action mailed September 9, 2004 (Paper No. 09072004), Applicant hereby elects, without traverse, Group I, claims 1 to 11, for continued examination. An early and favorable action on the merits is respectfully requested.

Dated: October 18, 2004

Respectfully submitted,

By Joseph W. Ragusa
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